

Gas Processor

To obtain higher energy-yields beyond the normal gas combustion process, **ionized ambient air gases** (104) of Figure (3-31) is, now, exposed to and intermixed with **Fuel-Gases** (88) prior to **thermal gas ignition** (98) of Figure (3-38), as illustrated in (240) of Figure (3-31).

Figure (3-31)

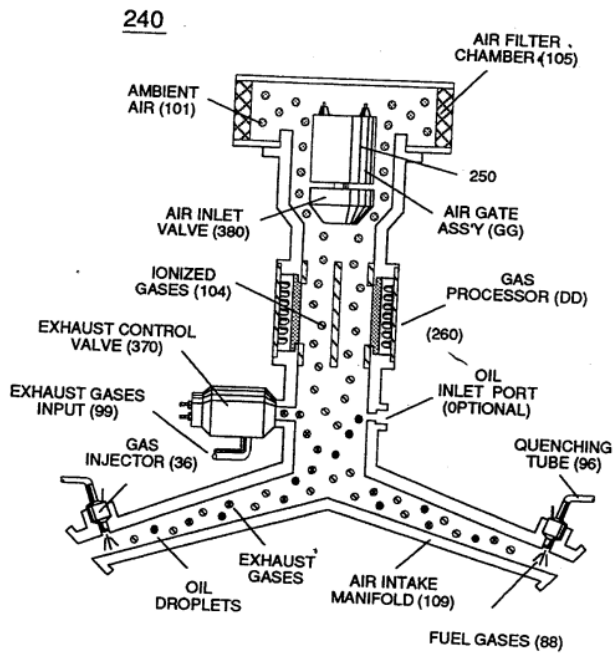


FIGURE 3-31: HYDROGEN GAS INJECTION SYSTEM

Figure (3-38)

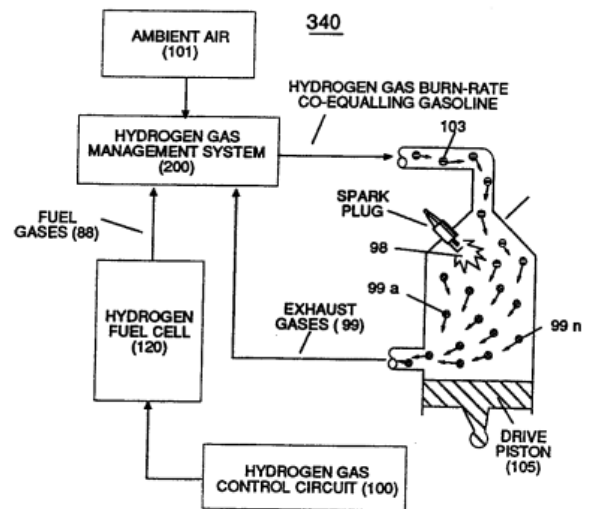


FIGURE 3-38: RETROFIT ENERGY SYSTEM

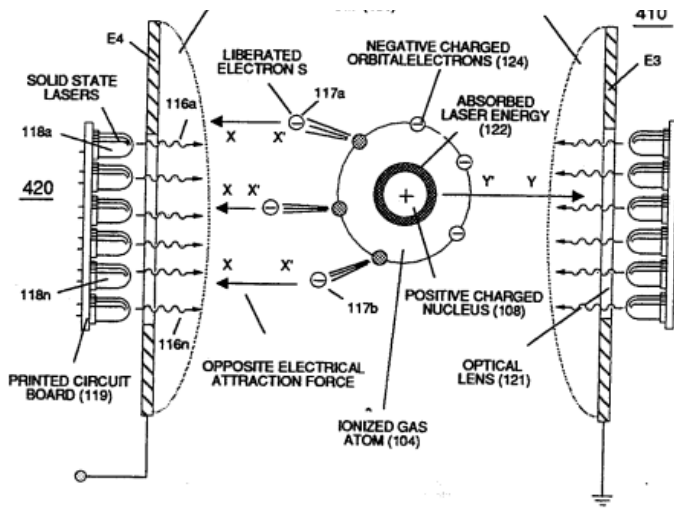


FIGURE 3-33: GAS PROCESSOR

As ambient **air gases** (101) enters into and

passes through air **filter chamber** (105) toward and beyond **air gate assembly** (GG), the moving **air gases** (101) are exposed to **high energy voltage fields** (*up to and beyond 2,000 volts*) (106/107) of **opposite electrical polarity** which causes ambient air gases to become **ionized gases** (104), as illustrated in (260) of Figure (3-33).

Positive electrical voltage field (106) causes **negative charged orbital electrons** (124a xxx) to be ejected from gas atom (101) due to opposite electrical attraction force (xx'); while, at the same time, negative electrical voltage field (107) exerts a second electrical attraction force (yy') on gas atom positive charged nucleus (108)

...opposite **electrical attraction forces** (xx') and (yy') being of equal intensity, as further illustrated in (260) of Figure (3-33).

Once electron ejection occurs, the liberated and free floating **electrons** (117a xxx 117n) continue to migrate toward **positive voltage zone** (106); whereas, the newly formed **ionized gas atom** (*having missing electrons*) (104) continues to move onward and through **air intake manifold** (109) of Figure (3-31) to **engine cylinder** (102) of Figure (3-38).

air intake manifold (109) of Figure (3-31)

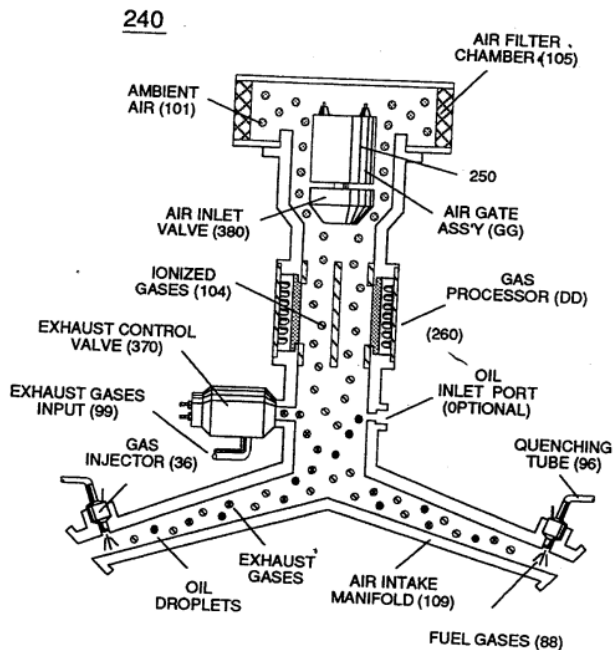


FIGURE 3-31: HYDROGEN GAS INJECTION SYSTEM

engine cylinder (102) of Figure (3-38)

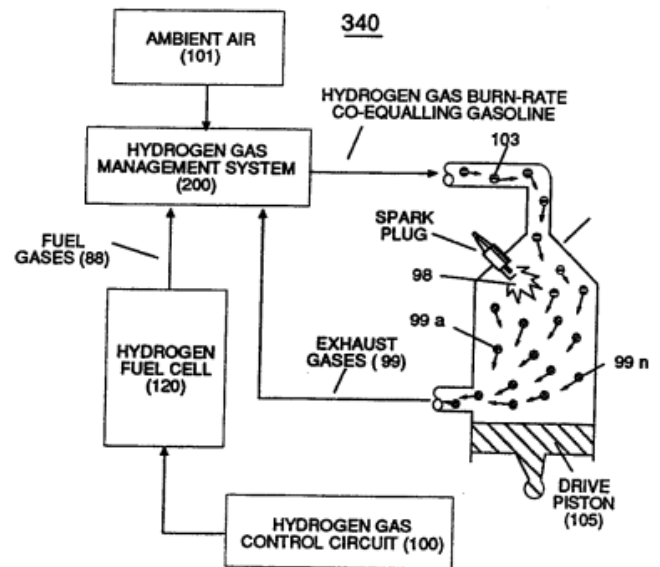


FIGURE 3-38: RETROFIT ENERGY SYSTEM

The resultant ionized **gas process** (260) of Figure (3-33) is performed by **Electron Extraction Circuit** (270) of Figure (3-34) which function in like manner to **Voltage Intensifier Circuit** (60) of Figure (3-22) except amp consuming device (390) (*such as a light bulb 11_2*) placed between **Resonant Charging Choke** (56) and **Gas Resonant Cavity** (410) of Figure (3-34) is added to **pulsing circuit** (60) to cause and convert **liberated electrons** (117a xxx 117n) into **radiant heat - energy** (*Kinetic energy*) (113) in the form of light energy (114)

Electron Extraction Circuit (270) of Figure (3-34)

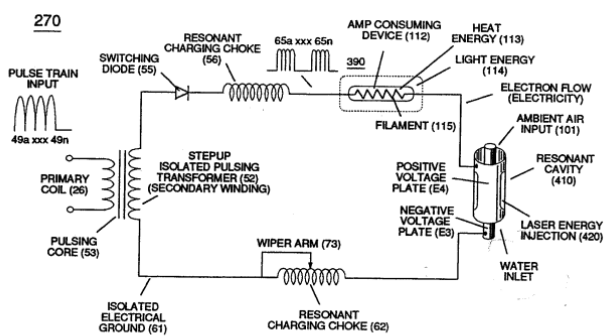


FIGURE 3-34: ELECTRON EXTRACTION CIRCUIT

Voltage Intensifier Circuit (60) of Figure (3-22)

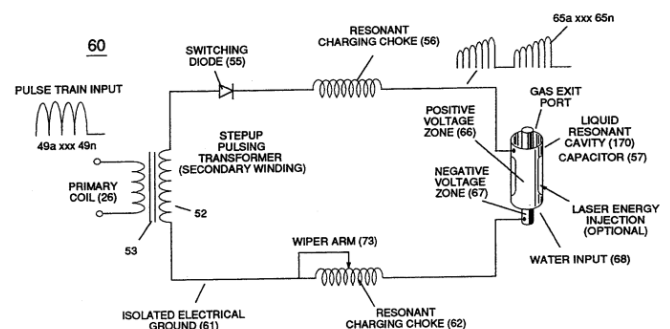


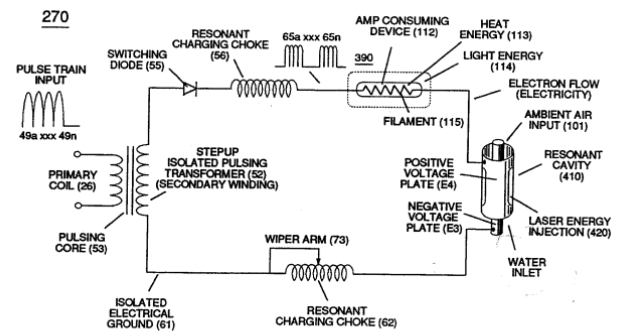
FIGURE 3-22: VOLTAGE INTENSIFIER CIRCUIT

... thereby preventing **electrons** (117a xxx 117n) from re-entering **ionized gas process** (260) ... destabilizing **gas atom** (101).

Repetitive formation of electrical voltage force or **voltage intensity** (65a xxx 65n) of Figure (3-21) attracts and causes **liberated electrons** (117a,xxx 117n) to move electrically away from **gas resonant cavity** (410) and physically interact with **light bulb filament** (115) to

initiate and perform **kinetic conversion process** (390), as further illustrated in (270) of Figure (3-34).

FIGURE 3-21: RESONANT CHARGING PULSE TRAIN



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The newly established and on-going **electron conversion process** (390) continues to aid **ionized gas process** (260) as other **gas atoms** (101a xxx 101n) are destabilized into **ionized gas vapor** (104a xxx 104n).

The **electron conversion process** (390) is, of course, terminated when applied pulse **voltage potential** (65) is switched off.

Pulsating voltage potential or **voltage intensity** (65a xx 65n) is adjusted, also, to "tune-in" to the resonant properties of **ambient air gases** (101) since **ambient air gases** (101) exhibits a dielectric value (air-gap of one inch resisting electron arc-over of up to 17,000 volts applied) between **voltage plates** (E3) and (E4), forming **capacitor** (410) of Figure (3-34).

Voltage fields (106/107) are physically configured (*skin effect*) by T304 stainless steel material to form **voltage plates** (E3/E4) of Figure (3-33) which are not only chemically inert to **gas ionization process** (260) but, also, forms tubular **Gas Resonant Cavity** (410) of Figure (3-34) having approximately the same size and shape of **liquid resonant cavity** (170) of Figure (3-25), as illustrated in (270) of Figure (3-34).

liquid resonant cavity (170) of Figure (3-25)

170

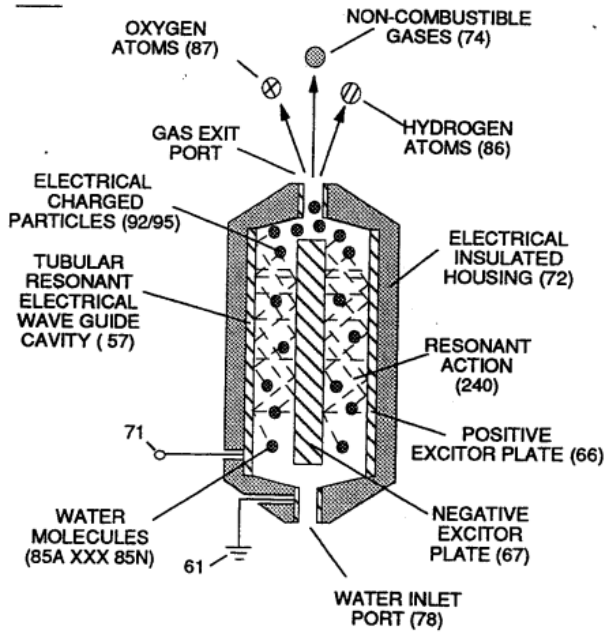


FIGURE 3-25: RESONANT CAVITY

(270) of Figure (3-34).

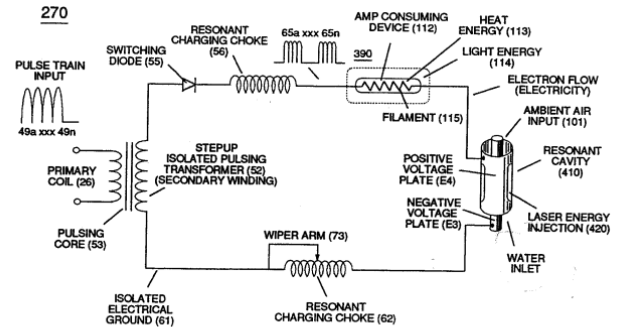


FIGURE 3-34: ELECTRON EXTRACTION CIRCUIT

To further destabilize **gas atom** (104), emitted laser energy (electromagnetic energy having zero mass) (116) is, now, injected into Gas Resonant Cavity (410) via optical lens (121) and superimposed onto gas ionized process (260) and subsequently absorbed by gas atom nucleus (108), as illustrated in (260) of Figure (3-33) as to (270) of Figure (3-34).

Figure (3-33)

260

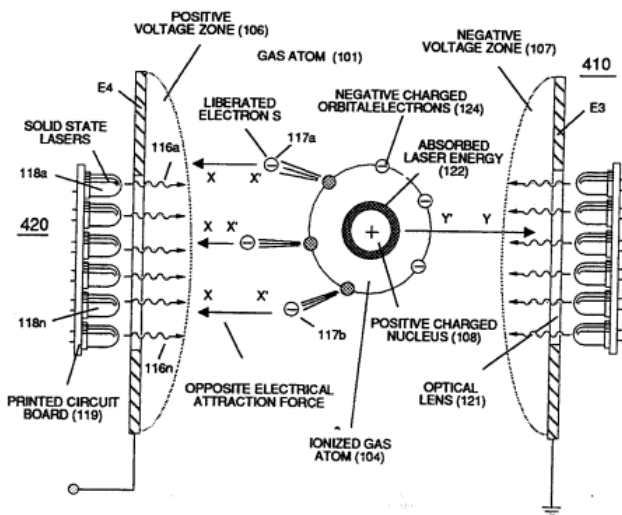


FIGURE 3-33: GAS PROCESSOR

(270) of Figure (3-34)

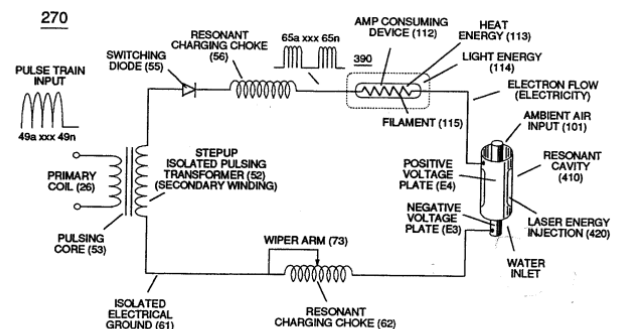


FIGURE 3-34: ELECTRON EXTRACTION CIRCUIT

The absorbed **laser energy** (122) of Figure (3-35) not only causes ionized **gas atom orbital electrons** (124) to be deflected away from **gas atom nucleus** (108) but, also, weakens **electrostatic force** (AA') between **gas atom nucleus** (108) and deflecting **electrons** (123a xxx)

... allowing even a greater number of electrons (117a xxx) to be ejected from ionized gas atom (104) being simultaneously subjected to Electron Extraction Process (260), as illustrated in (280) of Figure (3-35).

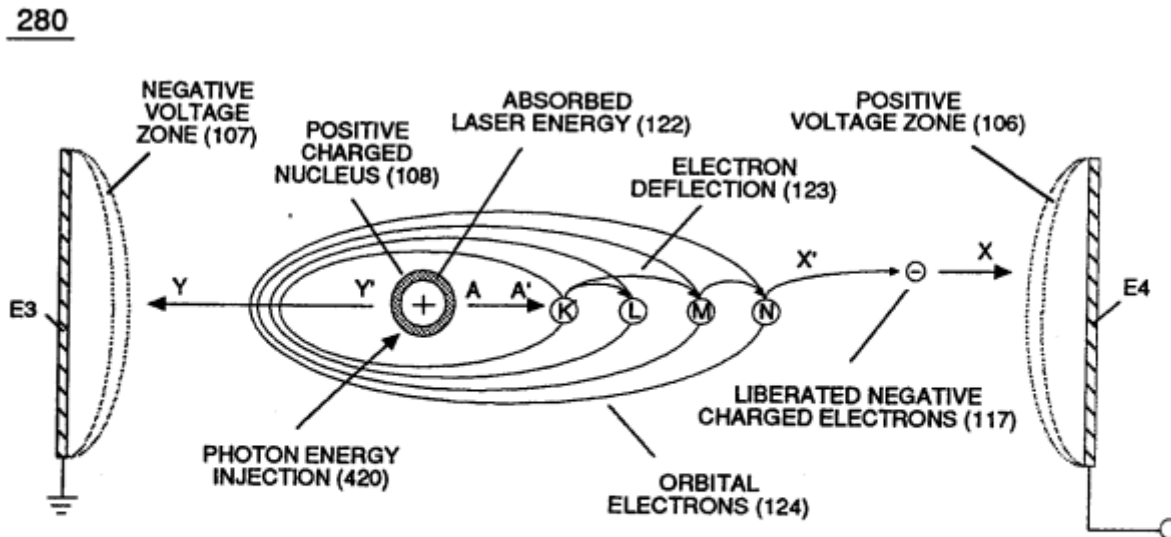


FIGURE 3-35: LASER INTERACTION

In essence, then, **laser interaction** (280) along with applied **voltage process** (260) causes **gas atom** (101) to go into sub-critical state (*destabilizing the mass entity of a gas atom*) since absorbed laser energy (122) prevents electrons re-capture (atoms accepting electrons) while **interfacing circuit** (270) dislodges, captures, and immediately consumes **ejected electrons** (117a xxx) In other words, **ambient air gases** (101) has, now, become **electromagnetically primed destabilized gas atoms** (104a xxx 100n) having missing electrons.

Solid state light-emitting diode (118) of Figure (3-33) arranged in a **cluster-array** (118a xxx 118n) mounted on **printed circuit board** (119) emits a discrete wave-length of light energy (*electromagnetic energy*) when **light circuit assembly** (420) of Figure (3-43) is **electrically pulsed** (126a xxx 126n) via **variable pulsing circuit** (125) in such a way as to vary **light intensity** (116) to match the light absorption rate of **ionized gas** (104), and, is determined with respect to the forward current through Led's (118) by (Eq 15)

(Eq 15)

$$R_s = \frac{V_{in} - V_{led}}{I_{led}}$$

Where

I_{led} , is the specified forward current (typically 20ma per diode); V_{led} is the led voltage drop (typically 1.7 volts for red emitter's).

Ohm's law for **led circuit** in **parallel array**, and, is given by (Eq 16)

(Eq 16)

$$P_{watts} = V_{cc} I_t$$

Where

It is the forward current through led cluster-array; V_{cc} is volts applied (typically 5 volts)

Whereby

Laser or light intensity is variable as to duty cycle on/off pulse frequency from 1hz up to and beyond 10khz, and is given by (Eq 17)

I_e is light intensity in watts; T_I is current on-time; T_O is current off-time; and (I_{ON}) = RMS value of load current during on-period.

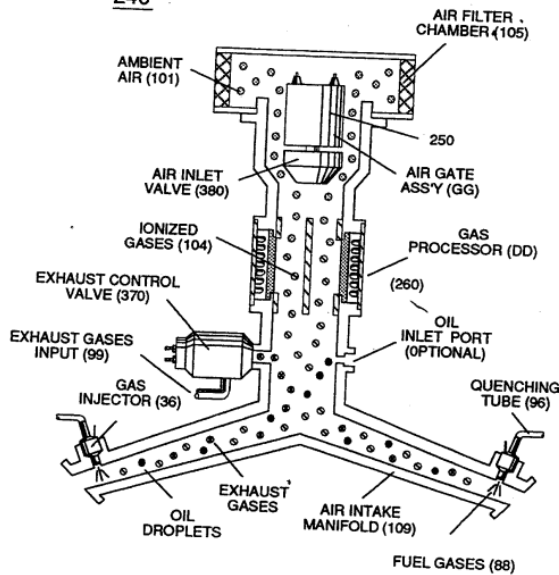


FIGURE 3-31: HYDROGEN GAS INJECTION SYSTEM

(Eq 17)

$$Le \sqrt{\frac{(ION)^2 \times T1}{T1 + T2}}$$

In terms of assembly, **gas resonant cavity** (410), **electron extraction circuit** (270), **optical lens** (121) forms **gas processor** (260) of Figure (3-31).

In retrospect to operational parameters, led's (118) light spectrum (extending from the visible into the Ultraviolet light region) can be selected for a given or predetermined **electromagnetically gas priming application** (280) since **gas nucleus** (108) is more responsive to coherent rather than diffused light source.

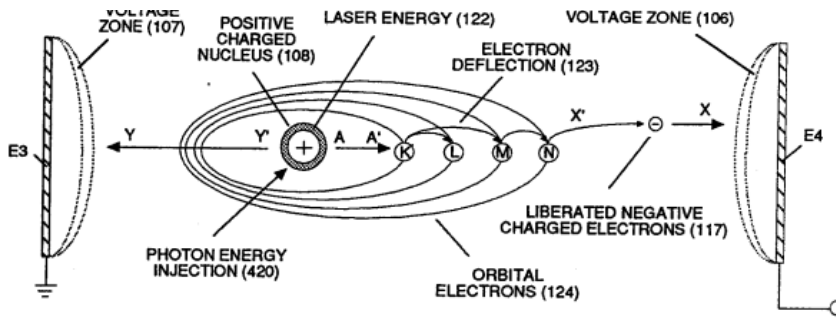


FIGURE 3-35: LASER INTERACTION

Applied **voltage amplitude** (V_a)

xxx V_n), applied voltage **pulse frequency** (65a xxx 65n), and applied **current pulse train** (126a xxx 126n) are design variable to "tune-in" to the resonant properties of **gas atom** (101) while stimulating and performing **gas process** (260) which attenuates **electrical force** (AA') of Figure (3-35) to disrupt the mass equilibrium of **gas atom** (104).

The resultant and newly formed **sub-critical gas atoms** (104a xxx 104n) are directed onward through **air intake manifold** (109) of Figure (3-31) to and beyond both **exhaust gas metering port** (370) and **injector port** (36) where **metered fuel-gas** (88), **metered exhaust gases** (99), and **metered sub-critical gas atoms** (104a xxx 104n) forms **gas-mixture** (103) entering **engine cylinder** (102), as illustrated in (240) of Figure (3-31) as to (340) of Figure (3-38).

(240) of Figure (3-31)

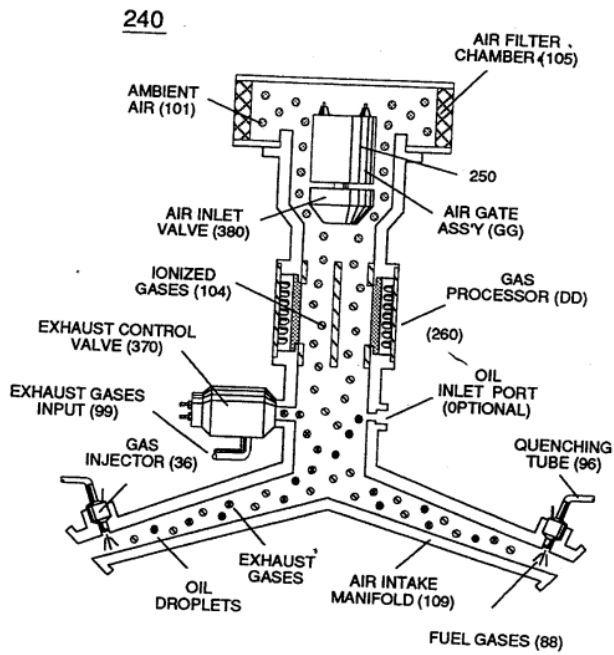


FIGURE 3-31: HYDROGEN GAS INJECTION SYSTEM

(340) of Figure (3-38)

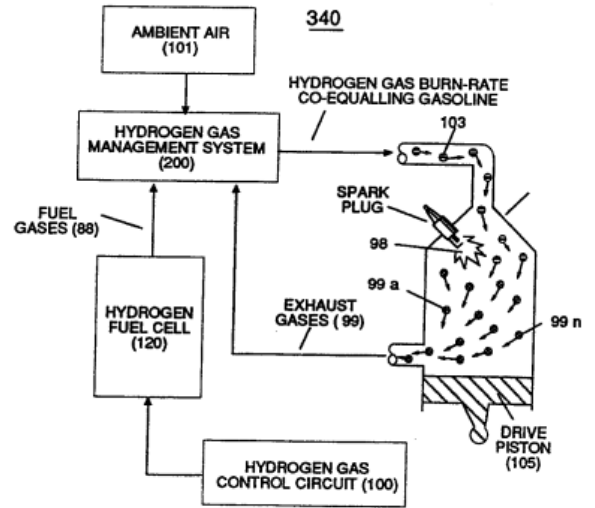


FIGURE 3-38: RETROFIT ENERGY SYSTEM

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